

ICS 77.120.99

CCS H 68

YS

**NONFERROUS METALS INDUSTRY STANDARD OF THE
PEOPLE'S REPUBLIC OF CHINA**

YS/T 839-2012

**Test method for measurement of insulator thickness and
refractive index on silicon substrates by ellipsometry**

硅衬底上绝缘体薄膜厚度及折射率的椭圆偏振测试方法

(English Translation)

Issued on: November 7, 2012

Implemented on: March 1, 2013

Issued by: Ministry of Industry and Information Technology

Table of Contents

What this standard covers	1
Document data	2

What this standard covers

This standard specifies test methods using ellipsometry measurements grown or deposited on the silicon substrate insulator film thickness and refractive index method. This standard applies to no absorption wavelength of the test film and the substrate on

Document data

International classification (ICS): 77.120.99.

Chinese classification (CCS): H68.

Estimated length of the Chinese original: 11,169 words.